

FORM PTO-1449
(Modified)

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U.S. Department of Commerce
Patent and Trademark Office

Attorney Docket No.: SLM-06100

Serial No.: 10/047,550

INFORMATION DISCLOSURE STATEMENT BY APPLICANT
(Use Several Sheets If Necessary)

Applicants: Gregory D. Miller et al

(37 CFR § 1.98(b))

Filing Date: January 15, 2002

Group Art Unit: 2881

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Examiner Initials		Serial / Patent Number	Issue Date	Applicant / Patentee	Class	Subclass	Filing Date
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	AB	Des. 334,742	04/13/93	Hunter et al.	D14	113	10/03/90
	AC	Des. 337,320	07/13/93	Hunter et al.	D14	113	10/03/90
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